

IN THE CLAIMS

Kindly **REPLACE** claims 1 and 9 with the following:

1. A silicon refining method comprising the steps of:
filling an unlined inductive crucible (1) with solid silicon;
melting the content of the crucible;
creating, by means of the inductive crucible, a turbulent stirring of the silicon melt (b) by
bringing the liquid from the bottom of the crucible to the free surface by ascending along
the central axis of the crucible; and
directing a plasma (f) generating by an inductive plasma torch (2) towards the melt
surface for a duration enabling elimination of impurities for which the reactive gas (g_r) of the
plasma is adapted.

9. A silicon refining installation comprising:
an unlined inductive crucible (1) adapted to receiving the silicon;
an inductive plasma torch (2) directed towards the free surface of the silicon load
contained in the crucible; and
a removable magnetic yoke (3) between the plasma torch (2) and the crucible (1) for
inverting a stirring direction of the silicon load, the yoke being ring-sharped to enable the passing
of the plasma flame (f).